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PATENT

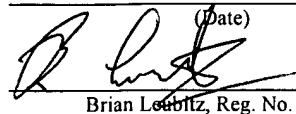
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoh et al.
Appl. No. : 10/759,953
Filed : January 16, 2004
For : SEMICONDUCTOR-
PROCESSING DEVICE
PROVIDED WITH A REMOTE
PLASMA SOURCE FOR SELF-
CLEANING
Examiner : Parviz Hassanzadeh
Group Art Unit : 1763

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

November 5, 2004

(Date)

Brian Leibel, Reg. No. 54,264

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed on August 11, 2004, please amend the above-captioned application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 8 of this paper.